

5th Workshop on LHCb upgrade II

30 .03 - 01 .04. 2020
Barcelona

Cooling, Detector Layout and Mechanics

Oscar Augusto on behalf of the LHCb VELO group

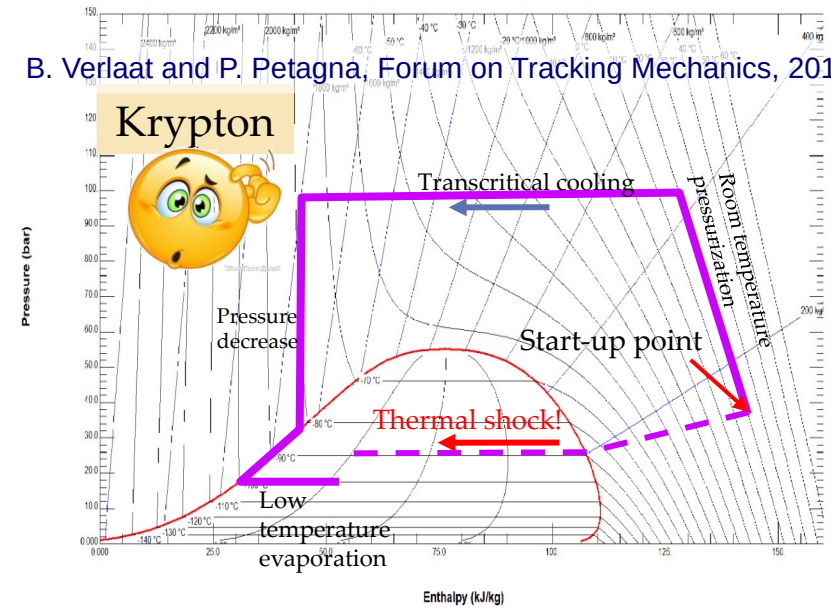
A grayscale, high-magnification photograph of a printed circuit board (PCB) showing intricate copper traces. The traces are arranged in a complex, repeating pattern of parallel lines that curve and bend, creating a maze-like appearance. The lighting highlights the metallic texture and the precision of the manufacturing process. In the center of the image, the word "Cooling" is written in a large, bold, black sans-serif font, overlaid on a semi-transparent white rectangular background.

Cooling

Module cooling

- Target coolant temperature below -40C
- Evaporative CO2 cooling is reaching its limit (triple-point at -56C)
- New coolants R&D needed: N2O(-163.65), CF4(-184C), Krypton(-157.4C)

B. Verlaet and P. Petagna, Forum on Tracking Mechanics, 2019

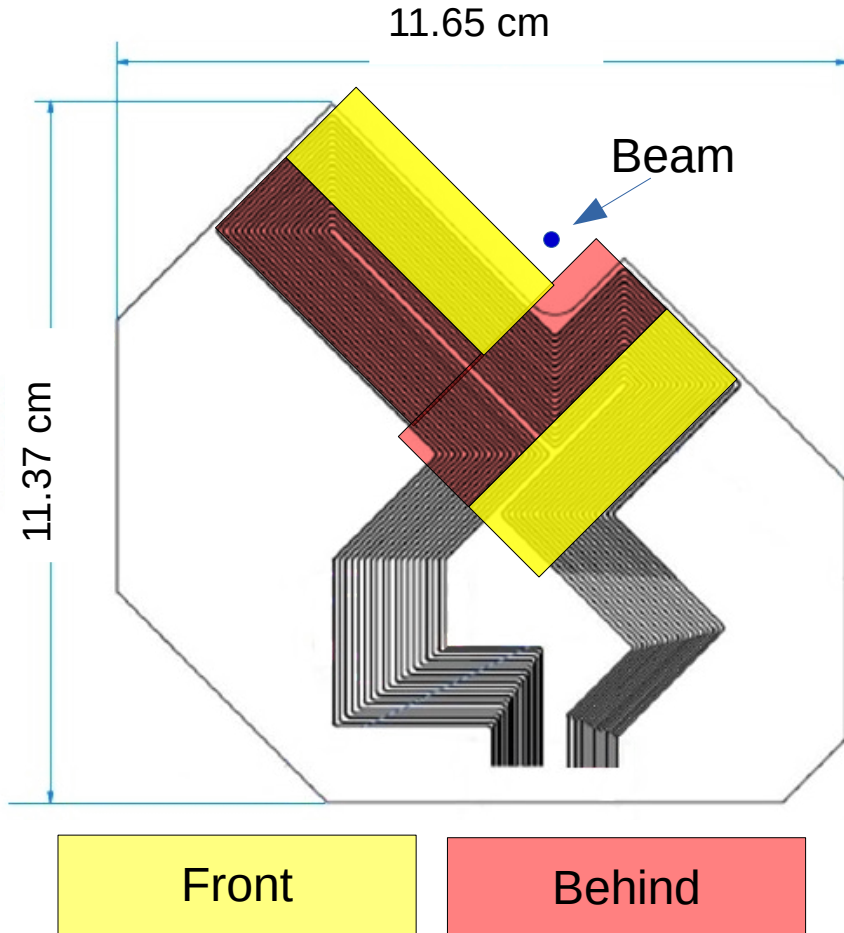


Cooling plate manufacturing

- Silicon microchannels vs 3D-printing
- Cooling performance, CTE mismatch, tile attachment, reproducibility
- Materials: Titanium, Ceramics, ...

	Si	Al	Ti	SiC
Thermal cond. (W/m.K)	149	237	6.8	120
Thermal Exp. (ppm/K)	2.6	23.1	8.9	2.8
Density (g/cm ³)	2.3	2.7	4.4	3.2

Microchannels etched in silicon

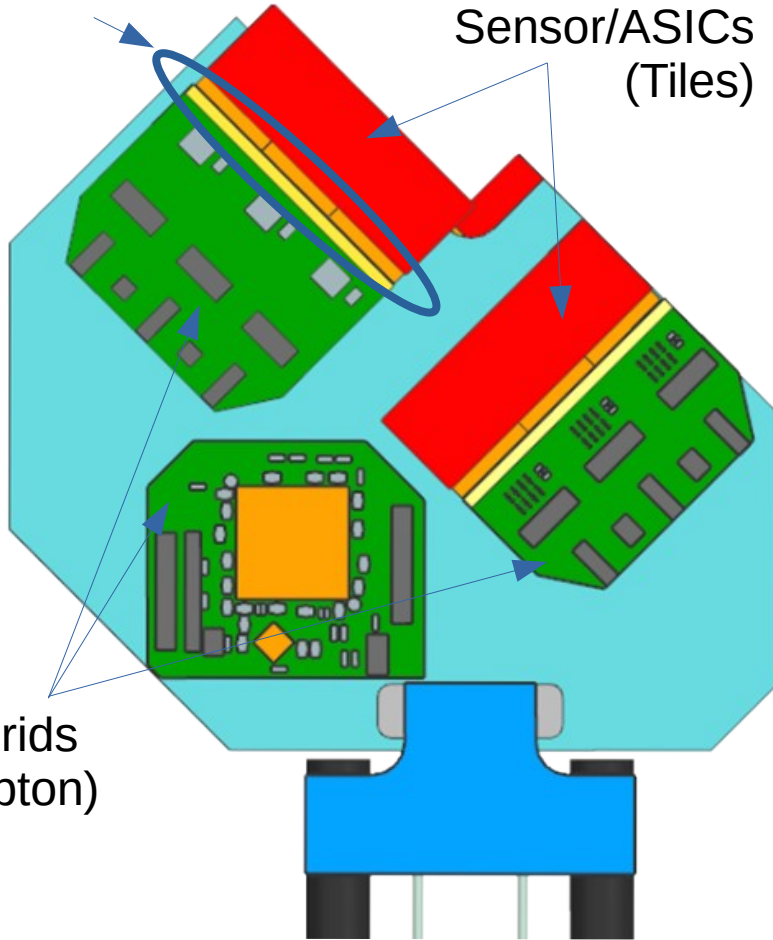


- Narrow restrictions at the entrance
- $60\ \mu\text{m} \times 60\ \mu\text{m}$ (40 mm long)
- Prevents instabilities among the channels
- Main channels
- $120\ \mu\text{m} \times 200\ \mu\text{m}$ (~260 mm in average)
- Heat provided by electronics is absorbed by the CO_2 changing the ratio of gas/liquid
- Advantages: High cooling performance, no CTE mismatch to the silicon sensors/ASICs, homogeneous and low mass
- Disadvantages: production cost, CTE mismatch to Hybrids (kapton) mechanically more fragile and integration

Microchannels etched in silicon

Wirebonds

Sensor/ASICs
(Tiles)

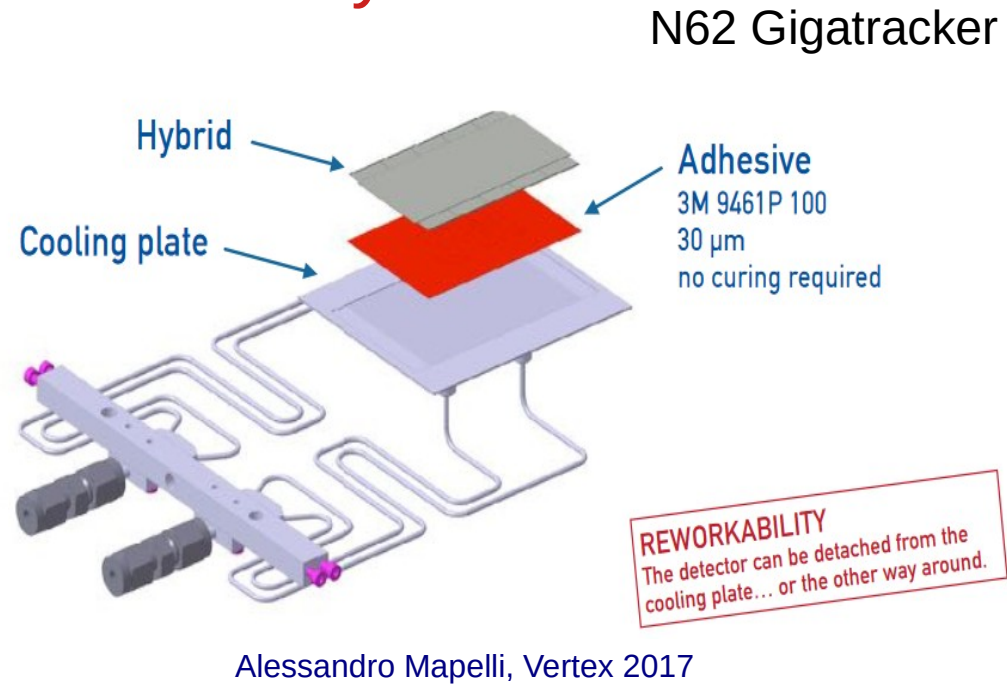


Hybrids
(Kapton)

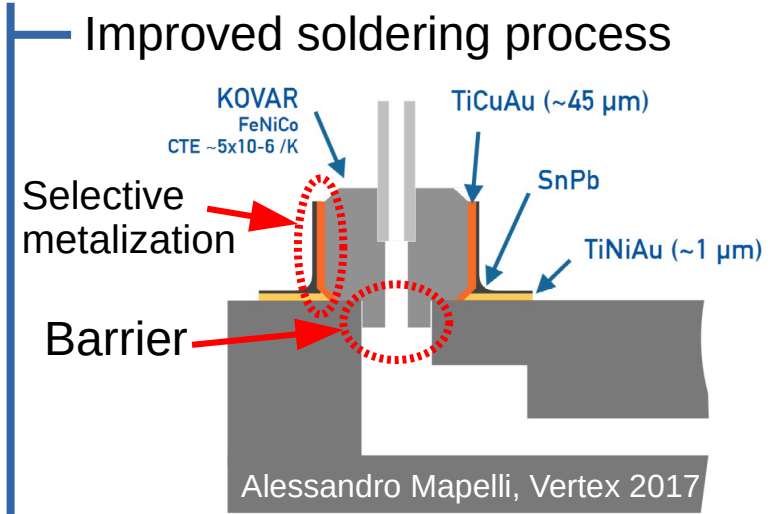
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Microchannels Silicon

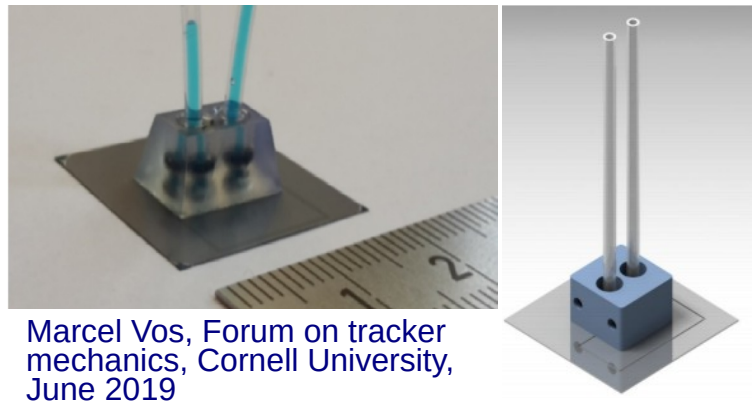
Reusability



Integration



3D printing connectors or mold



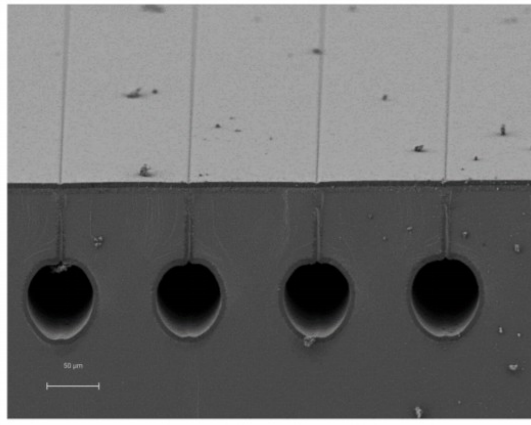
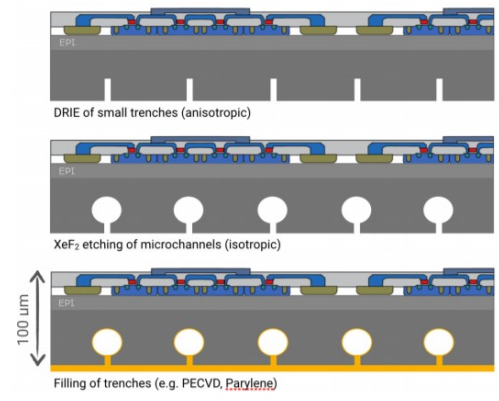
Microchannels Silicon

Production cost

- 1) Alternative Bonding (Anodic bonding, ...)
- 2) Smaller cooling plates

Buried microchannels

AIDA-2020-NOTE-2020-003

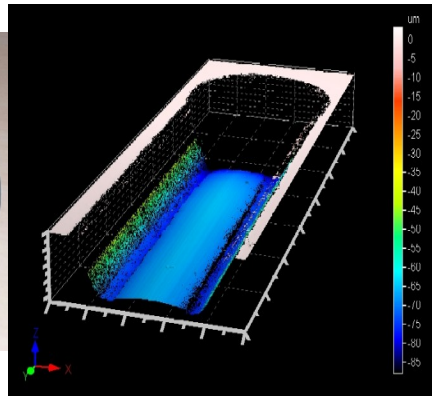
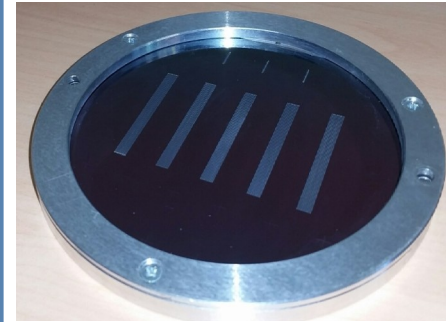


CMOS compatible process
Holds 110 bars
Demonstrator expected soon

**Most ambitious approach:
bring the cooling to the tiles**

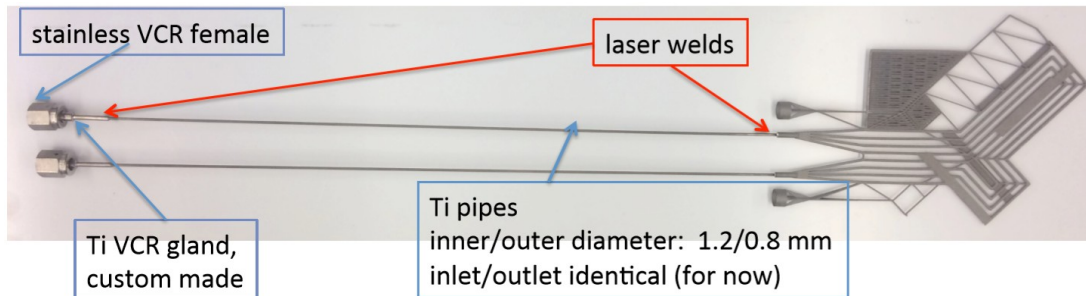
R&D @ CPPM

- 1) Laser etching and anodic bonding
- 2) 5 x 10 channels per wafer
- 3) 200 μm x 70 μm x 4.5 cm per channel
- 4) Next step: connector with anodic bonding

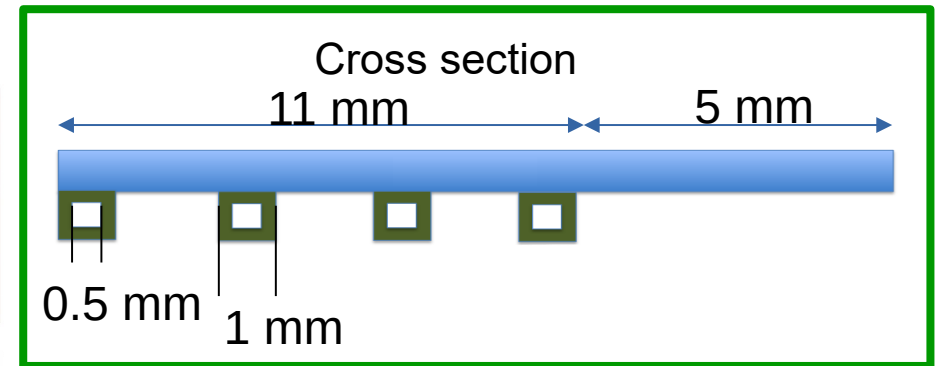
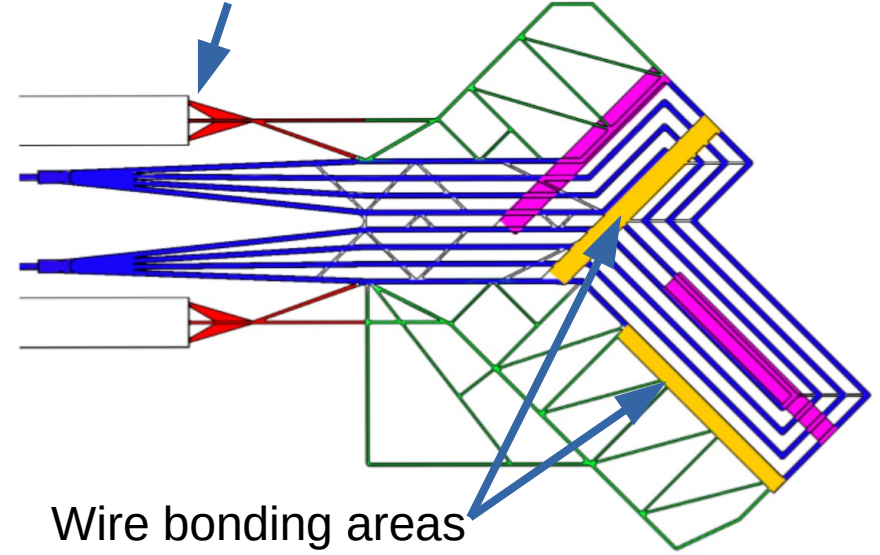


Ti 3D printing

- Material: grade 2 Ti
- Easier to handle (compared to Si)
- Easy to weld
- Cheap (~250 EUR excluding welding)
- Fast turnaround for design changes (few weeks)
- Fast production: 25/batch, 1 batch/few days
- Restrictions can be integrated in the inlet (0.35 mm x 0.35 mm x 40 mm)

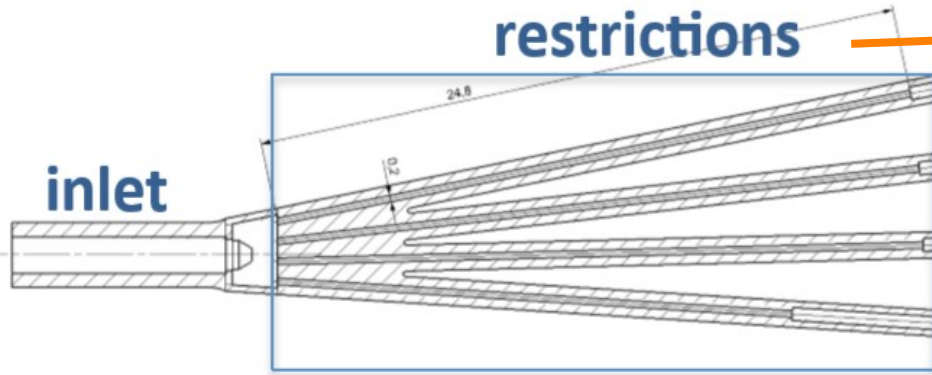
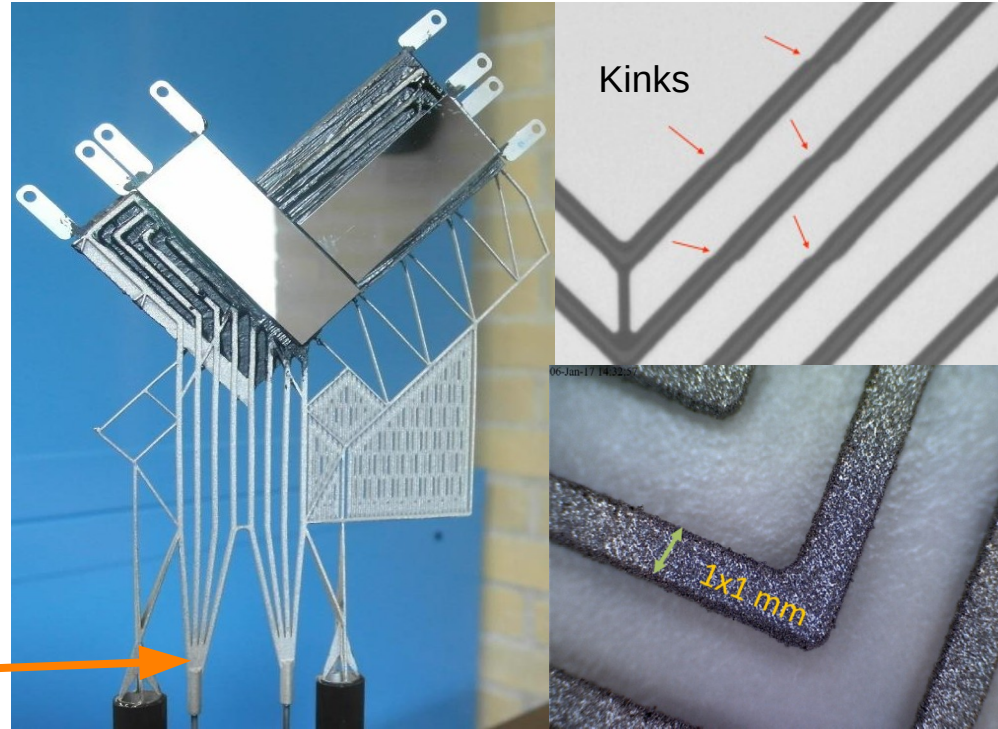


Mechanical support



Ti 3D printing

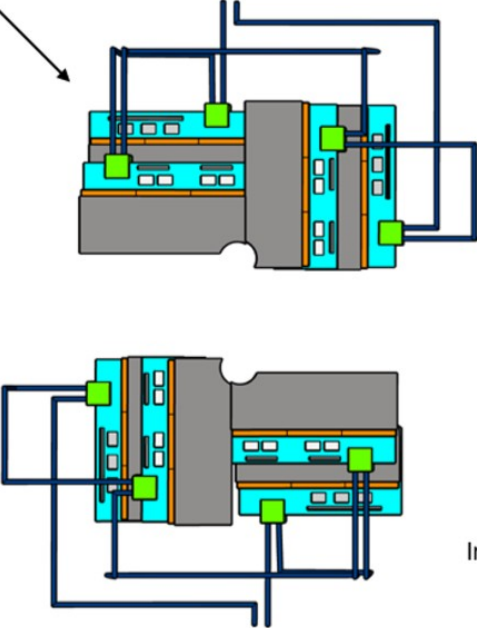
- 1) Integrated restriction for flow stability
 - a) down to $200\ \mu\text{m}$
- 2) High pressure test (up to 250 bar)
- 3) Leak tight (at least $250\ \mu\text{m}$ wall)
- 4) Deflection due to temperature variations $< 100\ \mu\text{m}$
- 5) Better CTE mismatch to the Hybrids



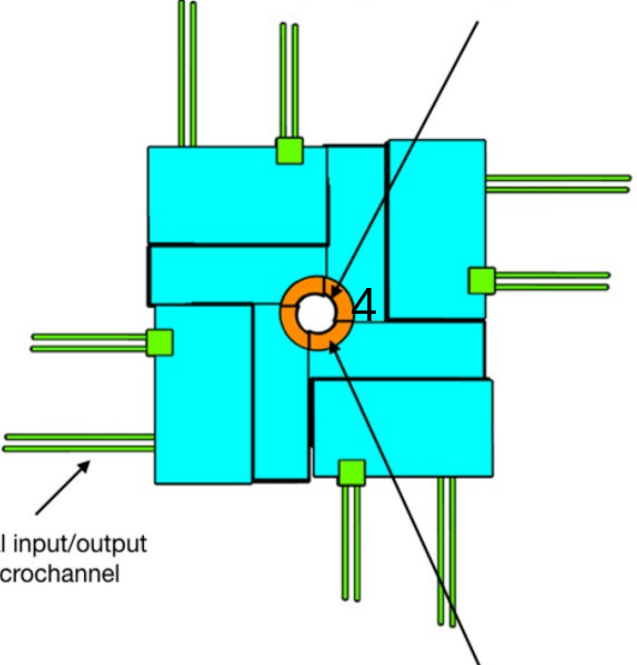
- Disadvantages:
- 1) Low thermal conductivity ($16\ \text{W/m K}$)
 - 2) CTE mismatch ($6\ \text{ppm/K}$) to Silicon / Glue
Corresponds to $\sim 14\ \mu\text{m}$ variation for Upgrade I
 - 3) Reproducibility

Modules geometry

Cooling flowing serially between micro channels



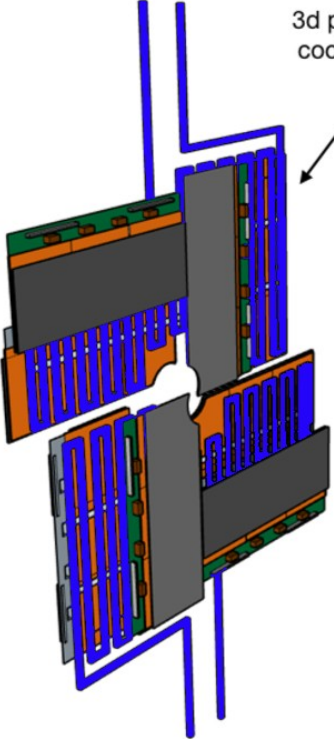
Bespoke dicing on ASIC (dicing lanes incorporated in design)



Individual input/output Per microchannel

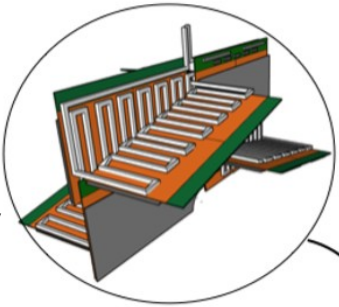
Overhanging sensor

3d printed titanium cooling backbone



Modules geometry

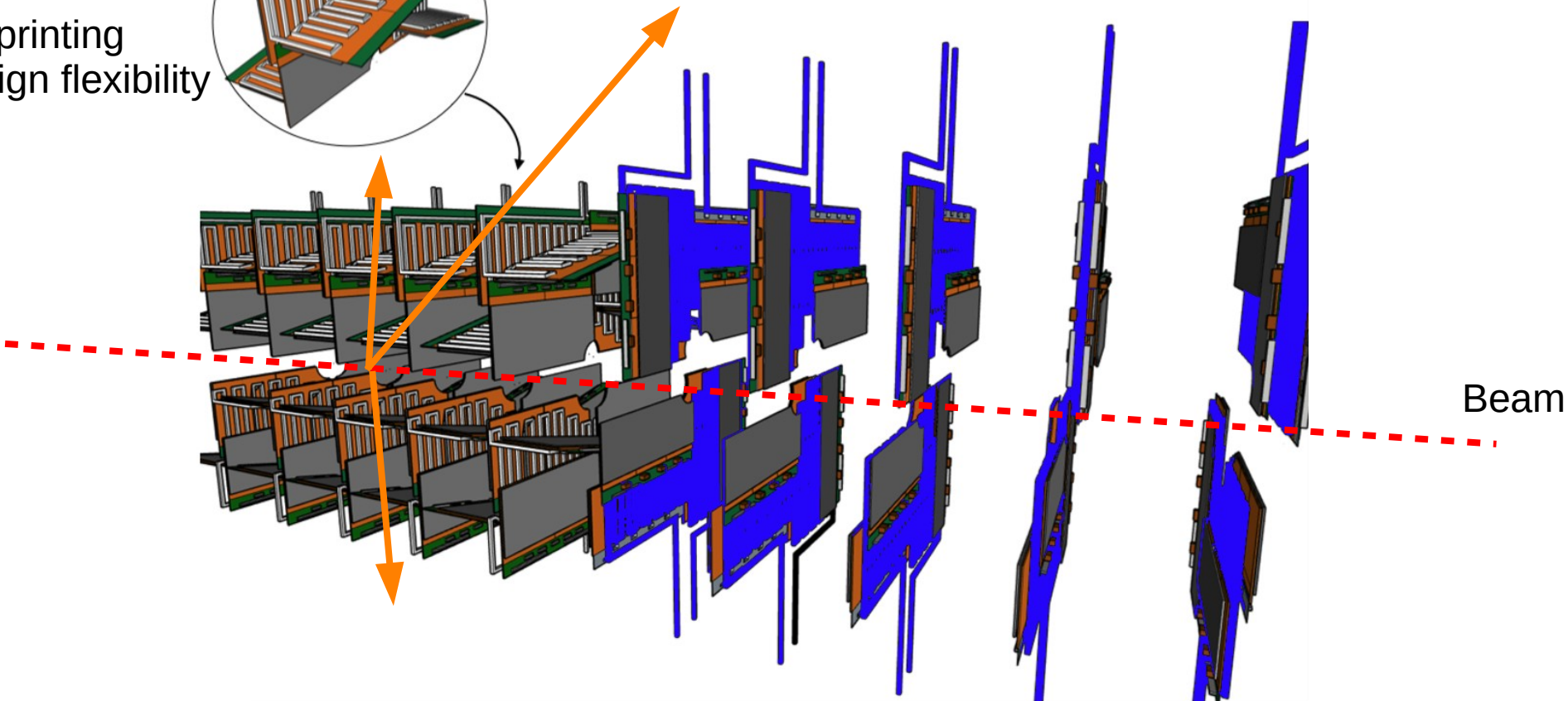
3D printing
design flexibility



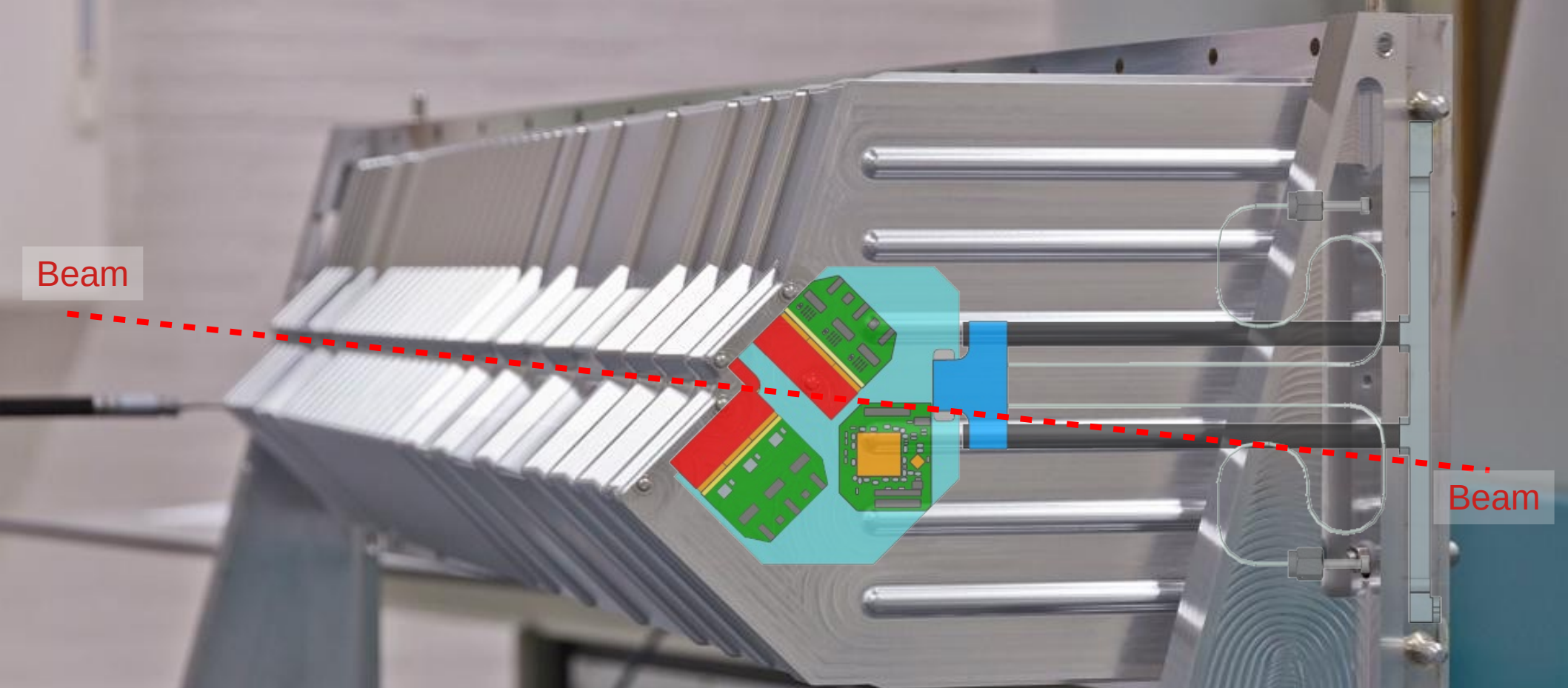
Higher reconstruction efficiency
for high opening angles



Higher primary
vertex reconstruction



Beam



Beam

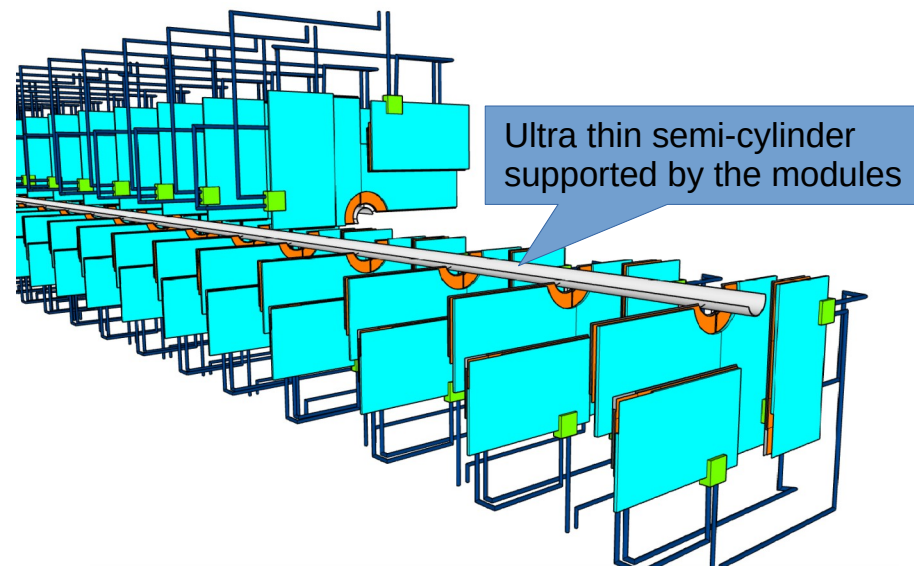
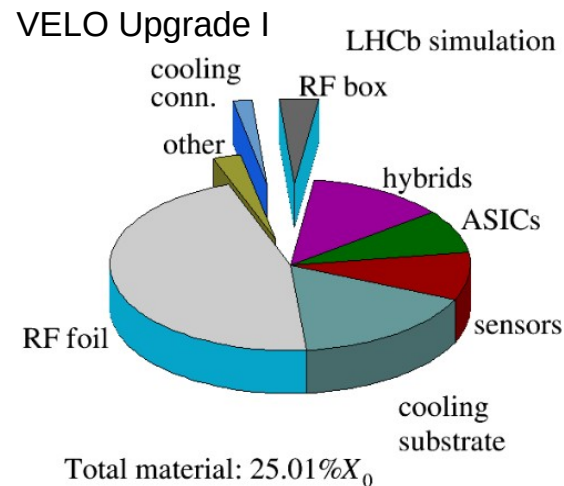
Beam

~~“To be, or not to be, that is the question”~~
Foil or no foil

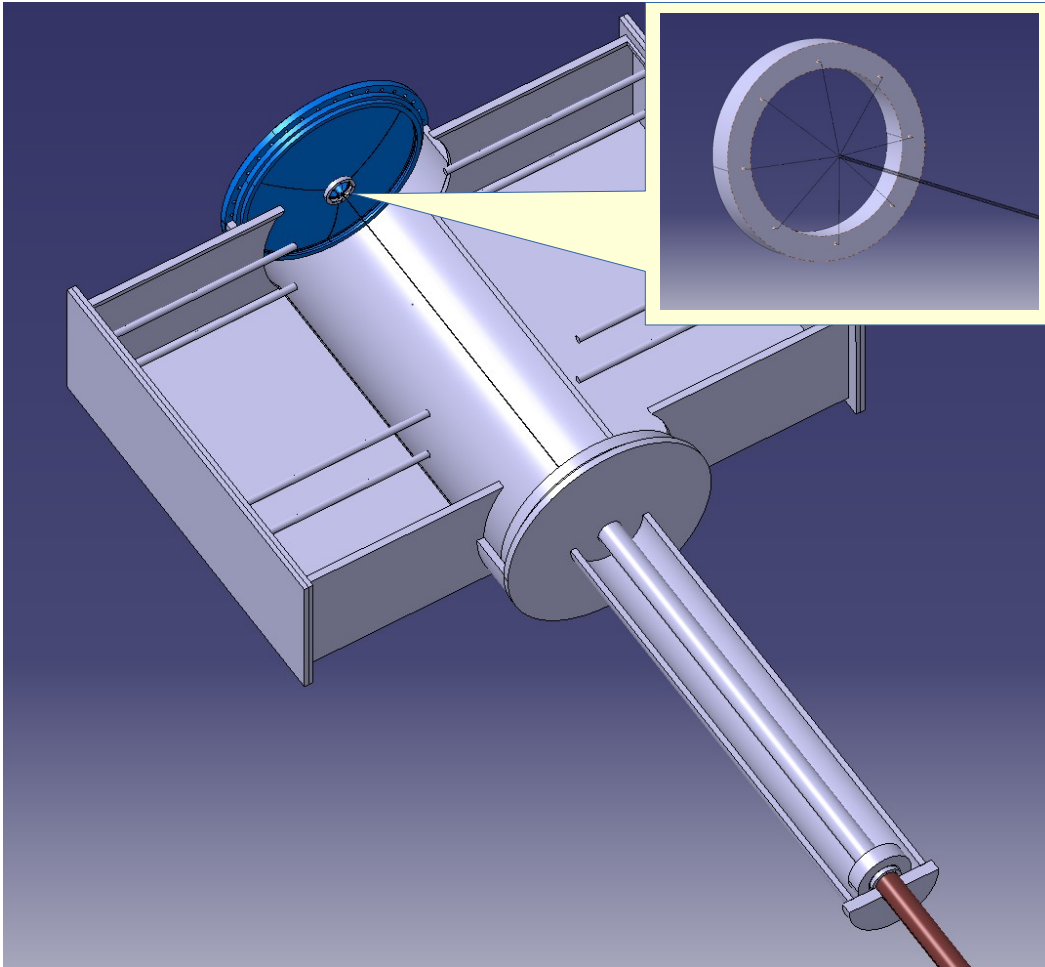
Hamlet

Foil or no foil

- No foil is better for the physics performance
 - Major contribution to the material budget for the VELO Upgrade I
- Module might come closer to the beam (better performance) or profit from the improved performance and move away to reduce radiation damage
- Critical for the design constraints and module replaceability. Radiation hardness changes:
 - 10^{16} neq/cm² (replaceable) vs 10^{17} neq/cm² (non-replaceable)
- A few ideas:
 - Ultra thin foil supported by the modules
 - Wires weave

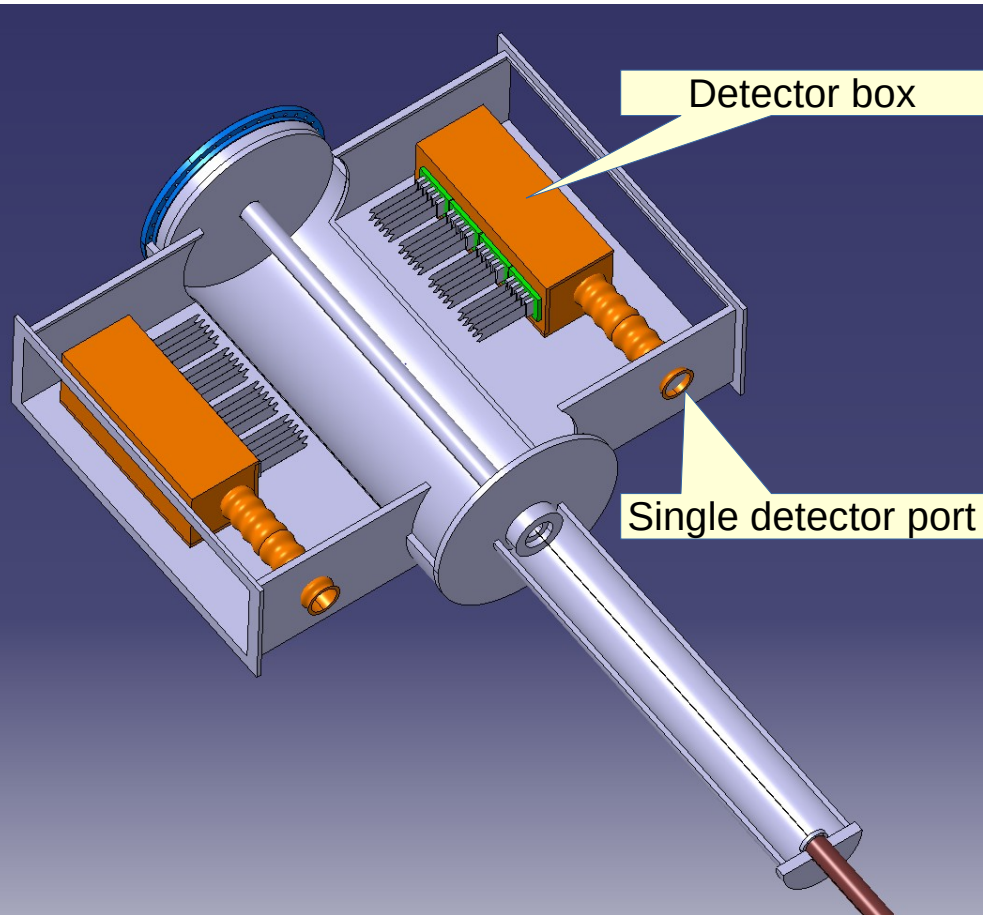


Piston and wires concept



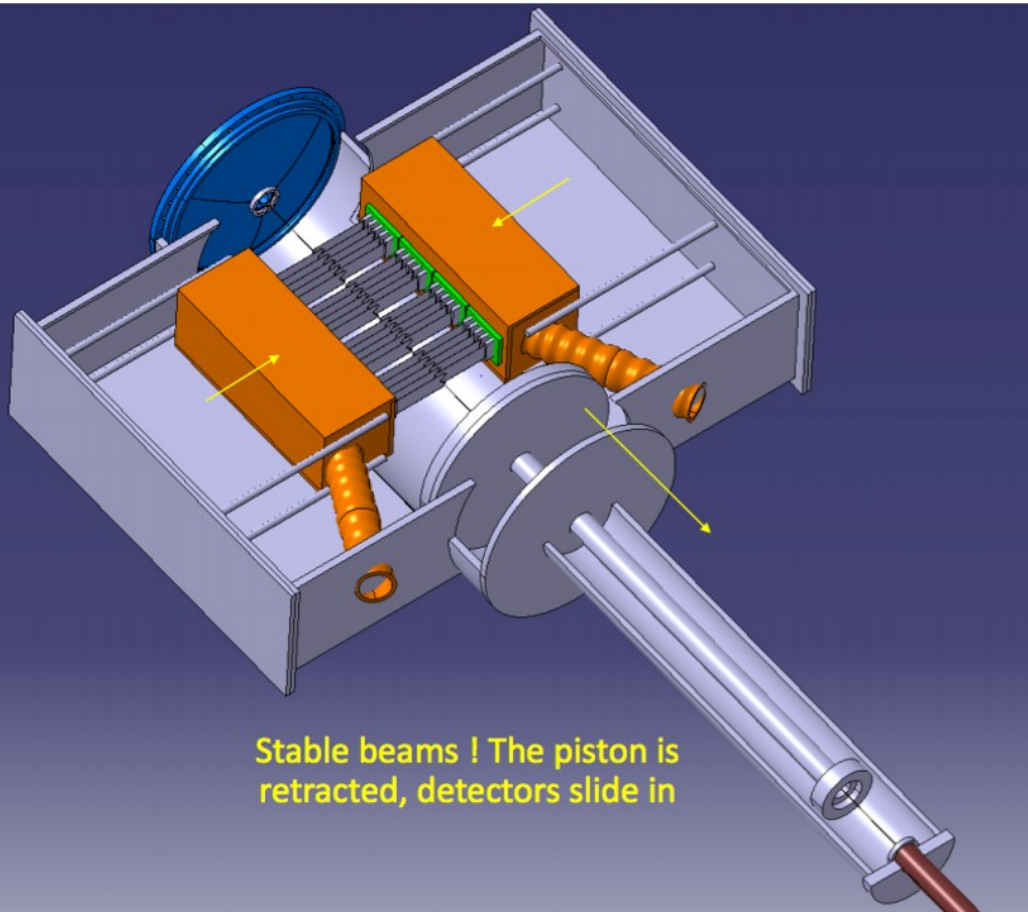
- 1) Detector is in beam vacuum
- 2) The image current travels through the foil replacement
- 3) Wires weaver
 - (a) Tungsten-Rhenium gold plated?
 - (b) Coated carbon fiber strips or tube?

Piston and wires concept



- 1) Detector is in beam vacuum
- 2) The image current travels through the foil replacement
- 3) Wires weaver
 - (a) Tungsten-rhenium gold plated?
 - (b) Coated carbon fiber strips or tube?
- 4) The detector is fully supported by a mountable leak tight detector box structure
 - (a) A spare would allow quicker replacement
- 5) The region below the module base has its own volume
 - (a) Outgassing from cables and additional electronics (OPB?) are isolated from the beam vacuum
 - (b) Cooling through dry-air flushing
 - (c) Cooling provided through the box
- 6) Single detector port

Piston and wires concept



Stable beams ! The piston is retracted, detectors slide in

- 1) Detector is in beam vacuum
- 2) The image current travels through the foil replacement
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 - (a) Tungsten-rhenium gold plated?
 - (b) Coated carbon fiber strips or tube?
- 4) The detector is fully supported by a mountable leak tight detector box structure
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 - (b) Cooling through dry-air flushing
 - (c) Cooling provided through the box
- 6) Single detector port
- 7) When beams are stable
 - (a) Piston is retracted
 - (b) Detector halves come closer to the beam

Conclusion

- 3D printing is very attractive
 - Cost effective for replaceable modules and design flexibility
 - Titanium is not the only option (Alumina, SiC, ...)
- Microchannels in silicon are not excluded
 - re-usability and/or cost reduction will be crucial
- Foil or No foil decision has critical implications for the design and module replaceability and mechanics
- New ideas are welcome even the crazy ones... :)

Thank you for your attention!

Backup slides

Micro-cooling @ CPPM

Gregory Hallewell

Julien Cogan

Mathieu Perrin-Terrin

Olivier Leroy

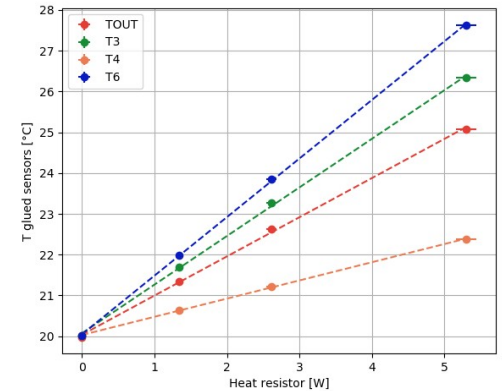
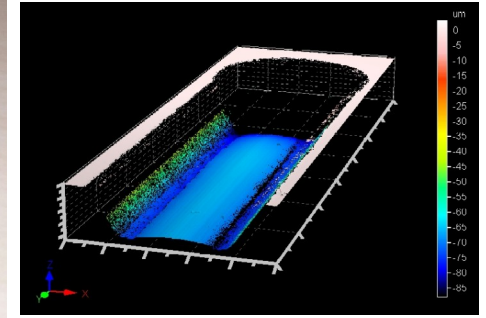
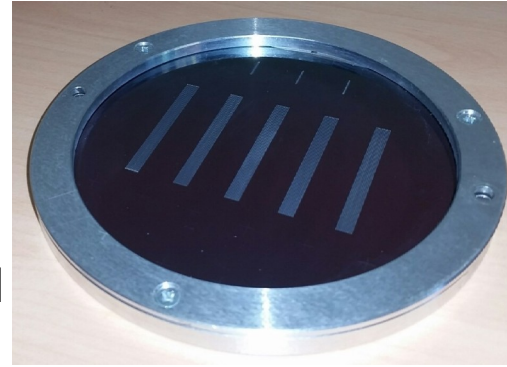
Stéphan Beurthey

March 2020

Laser etching

1st experience with micro-channels :

- laser etching of 2 4"-silicon wafers
 - 5x10 channels per wafer
 - 200 μm x 70 μm x 4.5cm per channel
 - pass-through holes at each channel end
 - with CNRS/LP3 lab, Marseille
 - anodic bonding of glass wafer (500 μm thick)
 - with Alessandro Mapelli at EPFL
 - thermal and flow tests
 - water circulated at a controlled temperature and flow rate
 - microchannel chips heated with a kapton heater
- good for prototyping but probably too slow and not cheap enough for production



Plans

On going: **anodic bonding of Si wafers with a thin intermediate layer of glass**

- 5 4"-Si wafers etched via DRIE
 - single-ended micro-channel for pressure test with various geometries
 - design compliant with pressure test bench used at CERN
- bonded in Germany
- *currently on hold, next:*
- thinning and dicing
- pressure test @ CPPM

Next, if previous step is successful: **start R&D on connector anodic bonding**